

Attorney Docket No. 01449/LH**IN THE UNITED STATES PATENT
AND TRADEMARK OFFICE**

Applicant(s): Toshihiko TANAKA

Serial No. : 09/917,845

Filed : July 25, 2001

For : DEFECT INSPECTION SYSTEM

Art Unit : 2133

Examiner :

**PRELIMINARY AMENDMENT AND
INFORMATION DISCLOSURE STATEMENT**Commissioner for Patents
Washington, D.C. 20231

S I R :

Please amend the above-identified application as follows:

IN THE CLAIMS:

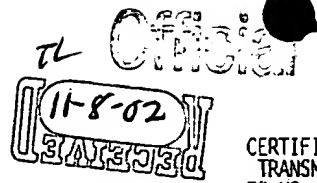
Please cancel claims 1-20, without prejudice, and substitute therefor the following new claims 21-36:

21. (New) A defect inspection system comprising:

an image acquiring section for acquiring a two-dimensional image of an entire surface of a subject which is a processing target in a manufacturing process;

an image storing section for storing, as image data, the two-dimensional image of the entire surface of the subject acquired by said image acquiring section;

a defect extracting section for extracting, as defect data, a defect of the surface of the subject based on a defect

CERTIFICATE OF FACSIMILE
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I hereby certify that this
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on the date noted below.

S. Lorraine Franklin

Dated: November 8, 2002

In the event that this Paper
is late filed, and the
necessary petition for
extension of time is not filed
concurrently herewith, please
consider this as a Petition
for the requisite extension of
time, and to the extent not
tendered by check attached
hereto, authorization to
charge the extension fee to
Account No. 06-1378.

#9/a
11-14-02